

# 13th International Symposium on Measurement Technology and Intelligent Instruments

(ISMTEI-2017)

Website: [www.ismtii2017.com](http://www.ismtii2017.com) Email: [ismtii2017@163.com](mailto:ismtii2017@163.com)

Xi'an, Shaanxi, China

22-25 September, 2017

Xi'an is the capital of Shaanxi province and is one of the most important cities in China. It is Chang'an in ancient times, the capital region for 13 dynasties. It was also the eastern end of the Silk Road.

**ISMTEI-2017** will focus presenting scientific and engineering breakthroughs to develop the cutting edge in modern measurement technologies and intelligent instruments. The Symposium offers the precious opportunity for experts and students to discuss the state-of-the-art in a diverse range of measurement fields. The exhibition and industrial forum are held to demonstrate the latest measurement technologies and instruments around the world.

## Organized by

Xi'an Jiaotong University, China

Harbin Institute of Technology, China

HeFei University of Technology, China

## Important Dates

Submission of abstracts: January 31, 2017

Notification of abstract acceptance: March 31, 2017

Submission of manuscripts of Full Papers: May 31, 2017

Notification of Full Paper acceptance: 15 June, 2017

## Honorary Chairs

Prof. Zhu Li, China, China

Prof. Zhuoxian Zhao, China

## Conference Chair

Academ. Zhuangde Jiang, China

## Conference Co-Chair

Prof. Jiubin Tan, China

## Organization Chair

Prof. Shuming Yang, China

## Organization Co-Chair

Prof. Liandong Yu, China

Prof. Jian Liu, China

## Symposium Scope (includes but not restricted to)

- Micro and Nano Metrology
- In-process and Inline Metrology
- Management of Measurement Processes
- Optical Metrology
- Surface Metrology
- Automated Optical Inspection (AOI)
- Machine Vision and Image Processing
- Macro Metrology
- Intelligent Instruments for Automation
- Sensors and Actuators
- Calibration and Machine Tool Performance
- Material Characterization
- Education and Training in Metrology

## Registration Fees

Registration fee includes: Attendance at Technical Program, Welcome Party, Lunches, Dinners, Coffee breaks, Banquet, Technical Visits, Excursion, Abstracts Volume, Disc with Proceedings.

- Participants: 450USD
- Students: 300USD
- Accompanying Person: 200USD

## Publications

- IOP and Springer will offer special issues for selected papers published on Advanced Manufacturing Technology (AMT) and Measurement Science and Technology (MST).
- Selected papers on nanometrology will also be recommended to submit to Surface Topography: Metrology and Properties, Nanomanufacturing and Nanometrology.

## Technical Tours

- State Key Laboratory of Mechanical Manufacturing Systems Engineering
- The key laboratory of the Ministry of Education: Electronic Materials Research Laboratory